



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1112

Examiner: To Be Assigned

In Re PATENT APPLICATION Of:

Applicant(s) : LIU et al.

Serial No. : 08/958,460

Filed : October 28, 1997

For : HIGH DENSITY PLASMA  
CHEMICAL VAPOR  
DEPOSITION PROCESS

Attorney Ref. : JIA 462

RECEIVED

FEB 01 1999

GROUP REQUEST

*1/2 status letter*

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Please let us know the status of the above-identified application and when an  
Action may be expected.

Respectfully submitted,

Date: 1/29/99

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SMR:aas

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